Inventor: 10/822,208

Title: Deposition Apparatuses

Assignee: Micron Technology, Inc.

Docket No. MI22-2519

## INFORMATION DISCLOSURE STATEMENT

## References – See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included with the exception of U.S. patents and published U.S. applications (1273 Off. Gaz. Pat. Off. 55, 05 August 2003). No admission is made regarding whether all the submitted references are prior art.
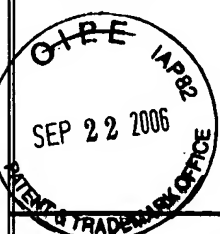
Respectfully submitted,

Dated: 9/22/06

By:

David G. Latwesen, Ph.D.
Reg. No. 38,533

EV832833824

09/26/2006 SSESHE1 00000010 10822208
01 FC:1806          180.00 OP

| Form PTO-1449 | U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE | ATTY. DOCKET NO. MI22-2519 | SERIAL NO. 10/822,208 |
|---|---|---|---|
| LIST OF ART CITED BY APPLICANT (Use several sheets if necessary) | | APPLICANT: Eric R. Blomiley, et al. | |
| | | FILING DATE April 8, 2004 | GROUP 1722 |

## U.S. PATENT DOCUMENTS

| *Examiner's Initials | | Document Number | Date | Name | Class | Subclass | Filing Date If Appropriate |
|---|---|---|---|---|---|---|---|
| | AA | 4,558,660 | 12/86 | Nishizawa et al. | | | |
| | AB | 5,061,872 | 10/91 | Kulka | | | |
| | AC | 5,364,667 | 11/94 | Rhieu, Ji H. | | | |
| | AD | 5,556,476 | 9/17/96 | Lei, et al. | | | |
| | AE | 6,021,152 | 02/00 | Olsen et al | | | |
| | AF | 6,108,490 | 06/00 | Subrahmanyam et al. | | | |
| | AG | 6,108.490 | 08/00 | Lee et al. | | | |
| | AH | 6,530,994 | 3/11/03 | Mahawili | | | |
| | AI | 6,994,769 | 2/06 | Singh, et al. | | | |
| | AJ | 2001/0010228 | 8/01 | Au et al. | | | |
| | AK | 2004/0000321 | 1/02 | Cui et al. | | | |
| | | | | | | | |

## FOREIGN PATENT DOCUMENTS

| | | Document Number | Date | Country | Class | Subclass | Translation | |
|---|---|---|---|---|---|---|---|---|
| | | | | | | | Yes | No |
| | AL | | | | | | | |
| | AM | | | | | | | |
| | AN | | | | | | | |

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

| | AM | | |
|---|---|---|---|
| | AN | | |

| EXAMINER | DATE CONSIDERED |
|---|---|
| | |

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

EV832833824

S:\MI22\\ID2.doc